

FORM PTO-1449

LIST OF PATENTS AND PUBLICATIONS FOR
APPLICANT'S INFORMATION DISCLOSURE
STATEMENT

(Use several sheets if necessary)

ATTY. DOCKET NO.

100203144-5

APPLICATION NO.

CONFIRMATION NO.

APPLICANT

Daniel Robert Blakely

FILING DATE

Herewith

GROUP

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	PUBLICATION DATE	NAME	Pages, Columns, Lines Where Relevant Passages or Figures Appear
	1A	02/0095618A1	Jul 18, 2002	Orcutt et al	
	1B	02/0093721A1	Jul 18, 2002	Knipe	
	1C	02/0075554A1	Jun 02, 2002	Brophy et al	
	1D	02/0067534A1	Jun 06, 2002	Holl et al	
	1E	01/0022682A1	Sep 20, 2001	McClelland et al	
	1F	02/0021058A1	Sep 13, 2001	McClelland et al	
	1G	6,388,789B1	May 14, 2002	Berstein	
	1H	6,201,629B1	Mar 13, 2001	McClelland et al	
	1I	6,040,935B1	Mar 21, 2000	Michalicek	
	1J	6,028,689B1	Feb 22, 2000	Michalicek et al	
	1K	6,014,240B1	Jan 11, 2000	Floyd et al	

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	PUBLICATION DATE	NAME OF PATENTEE OR APPLICANT	Pages/Columns/Lines Where Relevant Passages/Figures Appear	Check if Translation attached
	1L	EP1017038A2	Jul 05, 2000	Texas Instruments		
	1M	EP 0667975B1	Feb 19, 1997	Hahn-Schickard-Ges		
	1N	JP2002193899	Jul 14, 2000	Texas Instruments		
	1O					
	1P					

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

	1Q	K.E. Petersen, " Micromechanical light modulator aray fabricated on silicon", Applied Physics Letters, V. 31(8), Oct 15, 1977, pp 521-523
	1R	V.P. Jaecklin et al, "Optical Microshutters and Torsional Micromirors for Light Modulator Arrays", Proc. IEEE Workshop on Micro Electro Mechanical Systems, Feb 7-10, 1993, pp 124-127.
	1S	R.R. A.SYMS, "Equilibrium of Hinged and Hingeless Structures Rotated Using Surface Tension Forces", J. Microelectromechanical Systems, V. 4(4), Dec. 1995, pp 177-184.

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	2A	6,002,507B1	Dec 14, 1999	Floyd et al	
	2B	5,796,508B1	Aug 18, 1998	Suzuki	
	2C	5,629,790B1	May 13, 1997	Neukermans et al	
	2D	6,259,550	July 2001	Gotfried et al	
	2E	6,154,302	Nov 2000	Yagi et al	
	2F	6,600,851	July 2003	Aksyuk et al	
	2G	5,061,049	Oct 1991	Hornbeck	
	2H	5,430,571	July 1995	Witteveen	
	2I				
	2J				
	2K				

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	2L					
	2M					
	2N					
	2O					
	2P					

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

	2Q	A. Feinerman et al, "Fast Micro-mirrors with large angle deflections, http://www.darpa.mil/mto/stab/kickoff/stab_uic.pdf , Aug 8-9, 2000
	2R	D.C. McCarthy, "Photonic Switches: Fast, but Functional?" Photonics Spectra, March 1, 2001, pp 140-150
	2S	R.E. Brooks, "Micromechanical light modulators on silicon", Optical Engineering, V. 24(1), Jan-Feb, 1985, pp 101-106

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	3L					
	3M					
	3N					
	3O					
	3P					

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

3Q	A. Feinerman et al, "Agile Micro-Mirrors with Three Degrees of Freedom Manufactured with Liquid MEMS Technology" Free Space Laser Communication and Laser Imaging Proc. SPIE, V. 4489, 2002, pp 166-176
3R	
3S	

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